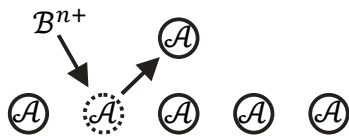


Ion Sources

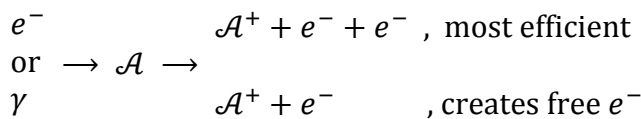
Ion Creation and -Confinement

Ion Creation

- ▶ supply neutral atoms \mathcal{A} by:
 - injection of gas
 - vaporizing
 - sputtering, i.e. bombard surface with other ion species \mathcal{B}^{n+}



- ▶ collide atoms with photons or electrons e^-



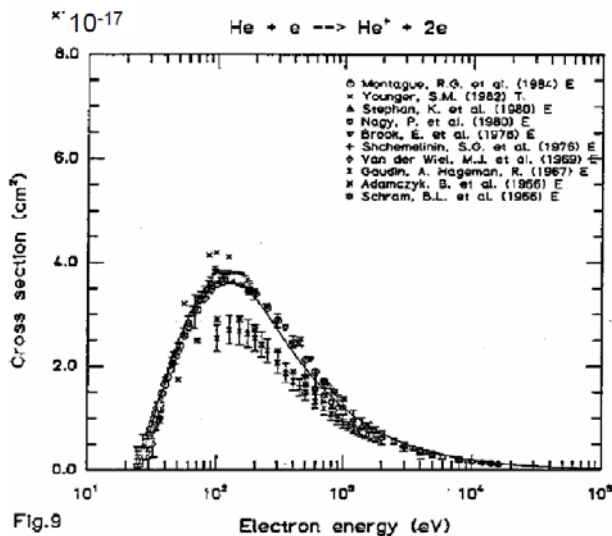
cross section of e^- - impact ionization (Lotz - formular):

$$\sigma_{\Delta q=1} = 4.5 \cdot 10^{-14} \text{ (eV cm)}^2 \cdot \sum_{i=1}^N \frac{\ln[E_{kin}/P_i]}{E_{kin} \cdot P_i}$$

E_{kin} = e^- kin. energy

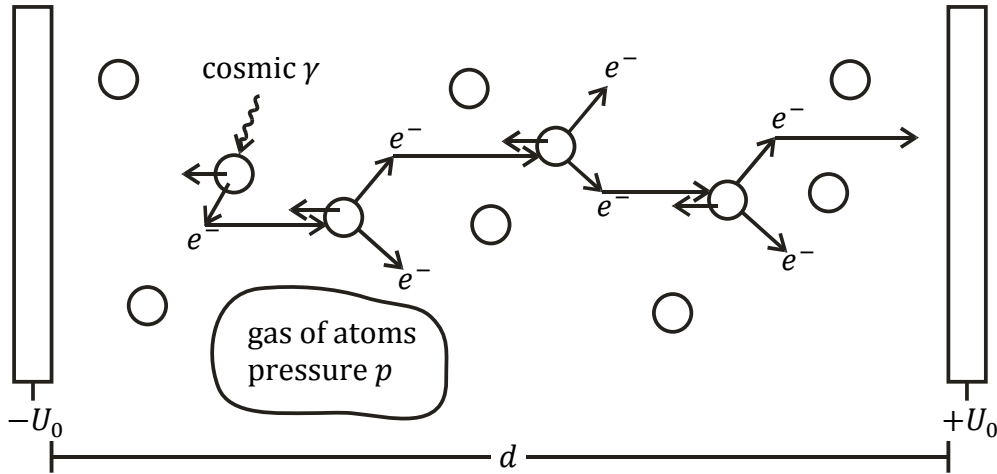
P_i = ionisation energy for e^- in orbit i

Single-ionisation: $\text{He} + e \rightarrow \text{He}^+ + 2e$



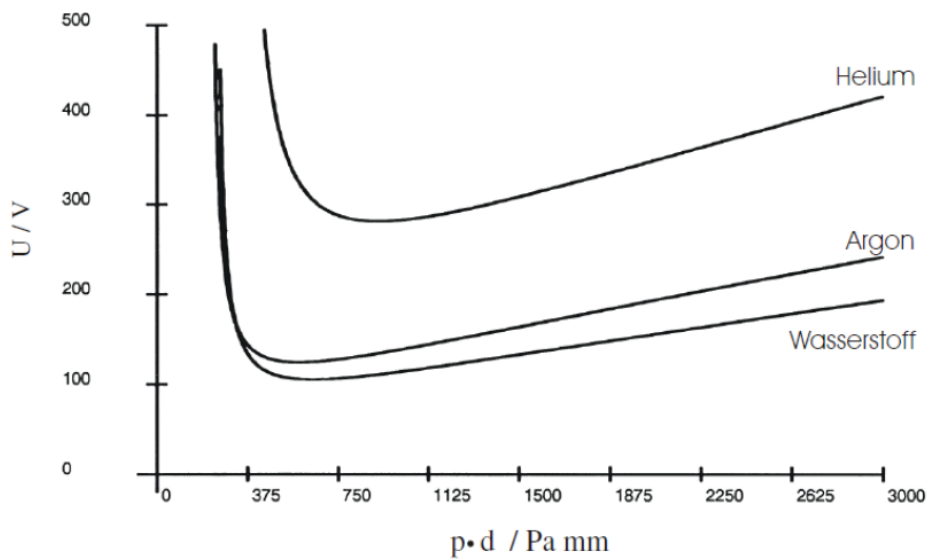
Ion Sources

Electron & Ion Production by controlled Discharge



if p & d are properly chosen
→ continuous e^- & ion production

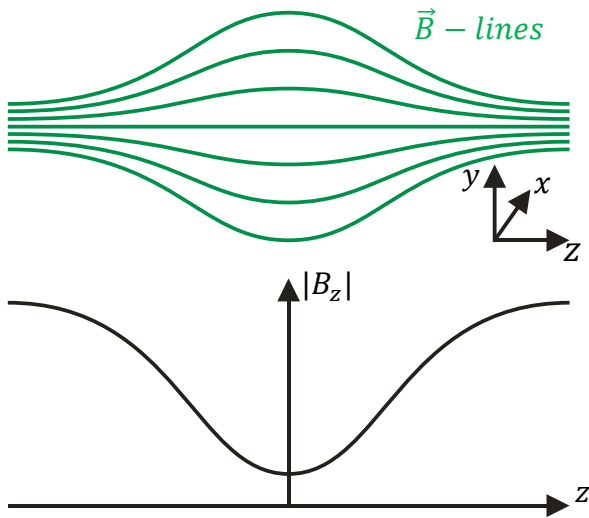
condition for discharge ignition (Paschen curve)



Ion (Plasma) Confinement

- ▶ without confinement ions & e^- move towards electrodes and get lost
- ▶ higher ion intensities require to confine ions inside “production” volume
- ▶ confinement by magnetic bottle:

Ion Sources



$$\frac{v_x^2 + v_y^2}{|B_z|} = \text{const}$$

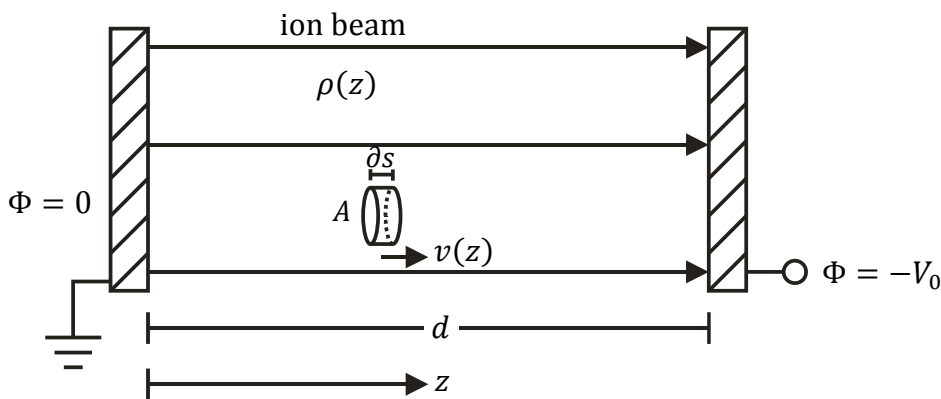
(see Jackson "class el. dyn.")

$$v_{tot}^2 - v_z^2 = |B_z| \cdot \text{const}$$

$$v_z^2 = \frac{2}{m} E_{kin} - |B_z| \cdot \text{const}$$

→ $|B_z| > B_c \rightarrow$ ion reflection along z-axis

Extraction of ions from planar surface



$$I(z) = \frac{\partial q}{\partial t} = \frac{\rho(z) \cdot A \cdot \partial s}{\partial t} = \text{const!}$$

$$\frac{I}{A} := J = \rho(z) \cdot v(z) = \rho \cdot \dot{z} = \text{const!} (*)$$

$$\Rightarrow \frac{\partial J}{\partial z} = 0 \text{ continuity equation (1)}$$

$$\vec{\nabla} \vec{E} = \frac{\rho}{\epsilon_0}, \quad \vec{E} = -\vec{\nabla} \Phi$$

$$\Rightarrow \Delta \Phi = \frac{\delta^2 \Phi}{\delta z^2} = -\frac{\rho}{\epsilon_0} \text{ Poisson equation (2)}$$

$$\frac{m}{2} \dot{z}^2 = -q \Phi(z) \text{ energy preservation (3)}$$

$$\Rightarrow \frac{\delta^2 \Phi}{\delta z^2} = \Phi'' = -\frac{\rho}{\epsilon_0} \stackrel{(*)}{=} -\frac{1}{\epsilon_0} \cdot \frac{J}{\dot{z}} \stackrel{(3)}{=} \frac{J}{\epsilon_0} \sqrt{\frac{m}{2q}} \cdot \frac{-1}{\sqrt{-\Phi}} \quad | \int () \Phi' \delta \Phi$$

Ion Sources

$$\frac{\delta^2 \Phi}{\delta z^2} := \Phi'' = \frac{J}{\epsilon_0} \sqrt{\frac{m}{2q}} \cdot \frac{-1}{\sqrt{-\Phi}}$$

$$\Phi'^2 = \frac{4J}{\epsilon_0} \sqrt{\frac{m}{2q}} \sqrt{-\Phi} + C$$

$$\Phi(z=0) = 0, \quad \Phi'(z=0) = 0 \quad \rightarrow \quad C = 0$$

$$\Phi' = 2 \sqrt{\frac{J}{\epsilon_0}} \sqrt{\frac{m}{2q}} \cdot \sqrt[4]{-\Phi}$$

$$-\frac{4}{3}(-\Phi)^{3/4} = 2 \sqrt{\frac{J}{\epsilon_0}} \cdot \sqrt{\frac{m}{2q}} \cdot z \quad (a)$$

$$\Phi(z=d) = -V_0$$

$$\Rightarrow -\frac{4}{3}V_0^{3/4} = 2 \sqrt{\frac{J}{\epsilon_0}} \cdot \sqrt{\frac{m}{2q}} \cdot d \quad (b)$$

$$\text{from } \frac{(a)}{(b)} \Rightarrow \Phi(z) = -V_0 \left(\frac{z}{d}\right)^{4/3}$$

$$\Rightarrow \boxed{J = \frac{4}{9} \epsilon_0 \sqrt{\frac{2q}{m}} \cdot \frac{V_0^{3/2}}{d^2}} \quad \text{Child-Langmuir Law of space charge limited extraction}$$

- ▶ used simplification of planar plates (electrodes)
- ▶ real electrodes:
 - are curved
 - have beam holes (extraction electrode @ $-V_0$)

→ real currents may be lower (ions)

but scaling law $J \sim V_0^{3/4} \cdot d^{-2}$ holds

$I = A \cdot J := P \cdot \frac{A_{\text{cathode}}}{d^2} \cdot V^{3/2}$, P is "Perveance"

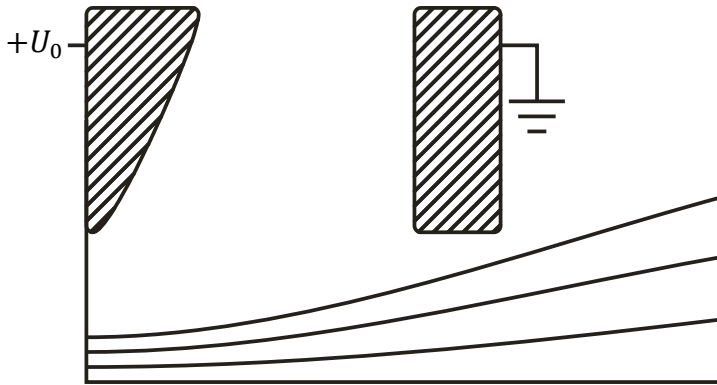
$P(\text{Child-Langmuir}, e^-) = 2.33 \cdot 10^{-6} \frac{A}{V^{3/2}} := 2.33 \mu\text{Perv}$

ion-energy and -current are coupled!

Ion Sources

extraction with one electrode is called "diode" extraction
 "di" \cong 2 \rightarrow 1. emitting electrode, 2. grounded electrode

diode extraction:



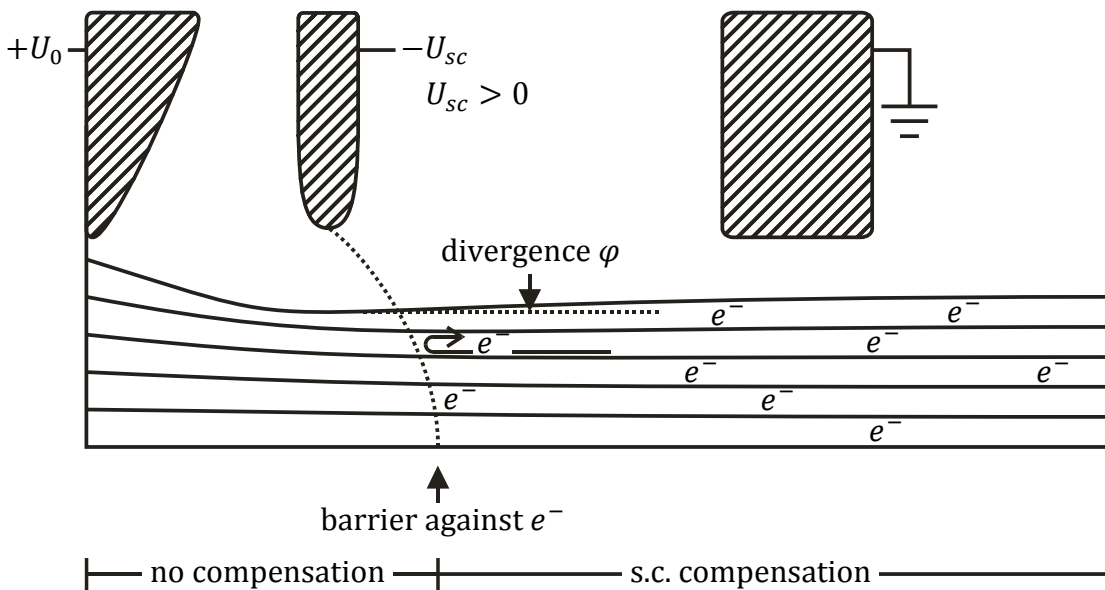
- ▶ I and E_{kin} are coupled, i.e. can't be set independently
- ▶ beam has strong repulsing self forces, called space charge (s.c.) forces
- ▶ space charge decreases beam quality (causes beam divergence)

beam ions collide with neutral residual gas atoms $\rightarrow e^-$ creation

- ▶ e^- reduce s.c.
- ▶ but e^- are pulled towards emitter $\rightarrow e^-$ are removed from beam
 \rightarrow s.c. is re-installed

Triode Extraction:

insert a screening (sc) electrode that keeps e^- off from emitter

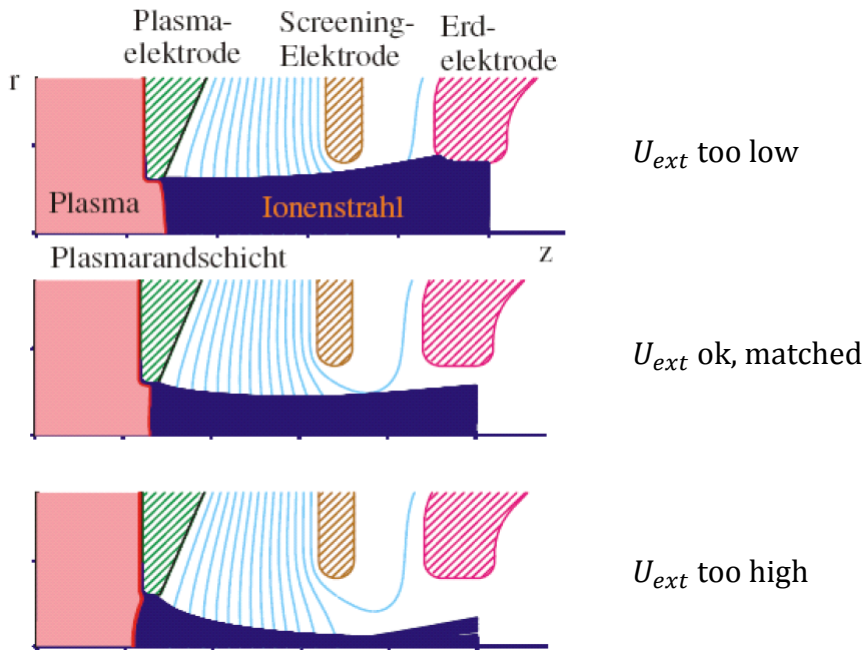


Ion Sources

- ▶ beam current from $U_0 - (-U_{sc}) = U_{ext,eff}$; effective extraction voltage
- ▶ beam energy from $U_0 - 0 = U_0$

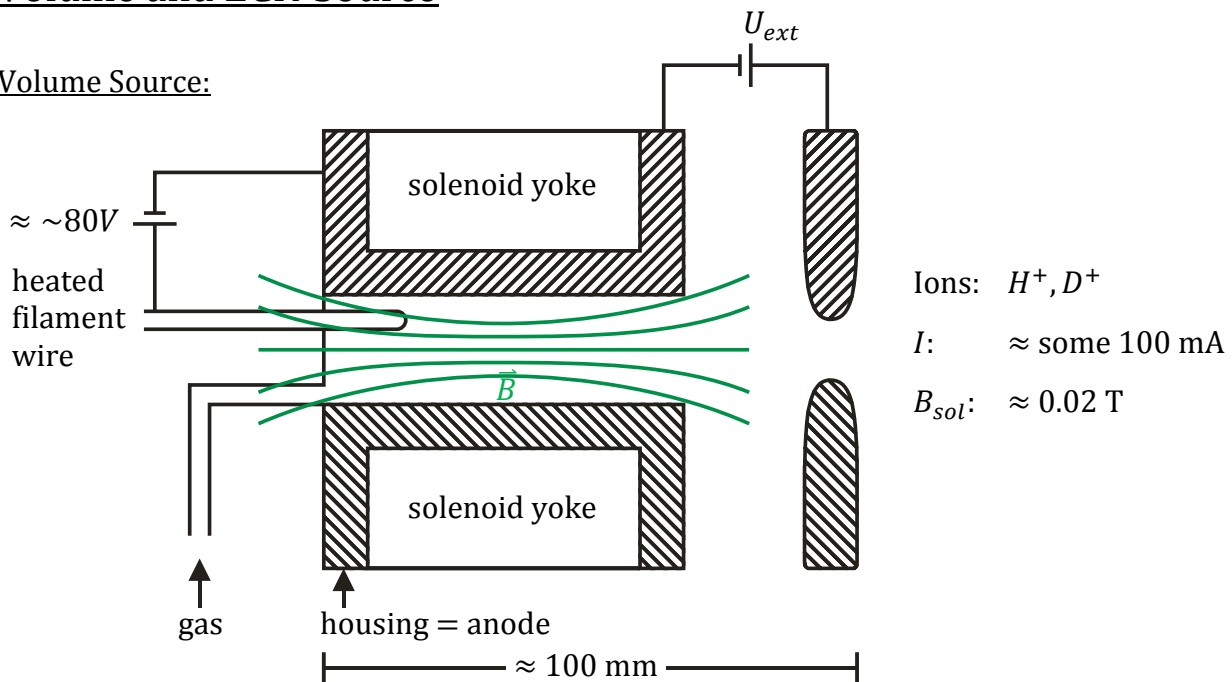
measure for beam quality:

- ▶ beam envelope divergence angle φ at e^- -barrier
- ▶ φ minimized \rightarrow matched case, $\varphi = \varphi(U_0, U_{sc})$



Volume and ECR-Source

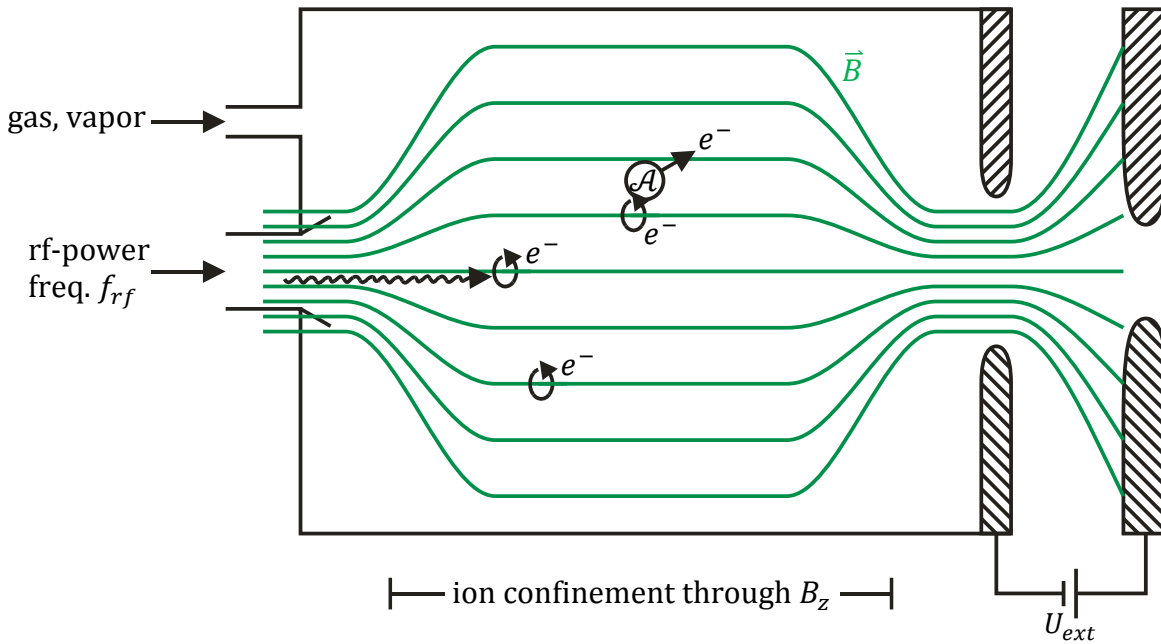
Volume Source:



Ion Sources

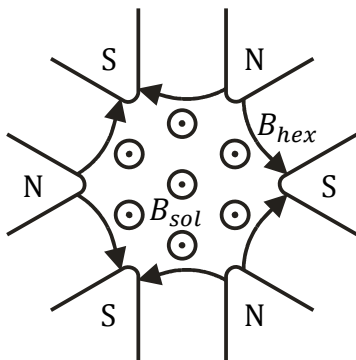
- ▶ filament provides free e^- for discharge
- ▶ solenoid field guides electrons

Electron-Cyclotron-Resonance (ECR) Source:



- ▶ rf-photons are absorbed by few free e^-
- ▶ absorption just if photon-frequency equal to cyclotron-frequency of e^- around field lines:

$$e \cdot v \cdot B_z = m_e \cdot \frac{v^2}{R} = m \cdot \omega_c \cdot v \Rightarrow \omega_c = \frac{e \cdot B_z}{m_e} \stackrel{!}{=} 2\pi f_{rf}$$
- ▶ repeated absorption by same e^- increases its E_{kin}
- ▶ e^- can ionize atoms to high charge states and create additional free e^-
- ▶ for intermediate and heavy mass ions \rightarrow additional hexapole-field for confinement



transverse hexapole-fields
improve confinement